2006 VLSI Technology Short Course TAPA I/II

Process Technologies for Continued Scaling and Performance

Monday, June 12, 2006, 9:00 a.m.

Organizers: Robert Chau, Intel Corporation

Toshihiro Sugii, Fujitsu Laboratories, Ltd.

9:00 a.m. Back-end Interconnect Technology

C.H. Jan, Intel Corp.

10:00 a.m. Break

10:15 a.m. Advanced Embedded Memories

K. Ishimaru, Toshiba Corp.

11:15 a.m. Lithography Solutions for 32nm and Beyond

M. Kameyama, Nikon Corp.

12:15 p.m. Lunch

2:00 p.m. Ultra-Shallow Junction Technologies

M. Kase, Fujitsu, Ltd.

3:00 p.m. Device Technology

S. Thompson, University of Florida

4:00 p.m. Break

4:15 p.m. High-k Gate Dielectrics

J. Lee, University of Texas at Austin

5:15 p.m. Conclusion